# Cee® 200CBX

# Precision Coat-Bake System



The Cee® 200CBX precision coat-bake system combines a track quality precision spin coater with a high uniformity bake plate, in an efficient space saving design.

Serving the Semiconductor Industry Since 1987

## **Benefits**

- Onboard Windows®-based PC control for enhanced interface capabilities and connectivity
- ▶ New compact design for minimized footprint
- ▶ Full-color, 7-inch touch screen display
- ▶ Teflon® spin bowl for maximum chemical compatibility
- Simultaneous operation and monitoring for both the coat and bake modules

#### **Dimensions**

- $\blacktriangleright$  28 in (71.1 cm) W  $\times$  19 in (48.3 cm) D  $\times$  12 in (30.5 cm) H
- ▶ Machine Weight: 165 lb (74.8 kg)
- ▶ Shipping Weight: 250 lb (113.4 kg)

## Programmability

- ▶ Controlled by onboard Windows®-based PC
- ▶ Touch screen interface and display
- Ethernet port for network connectivity and uploading/ downloading process parameters
- ▶ 250,000 process programs onboard
- ▶ Virtually unlimited steps per program
- 0.1-s resolution for step times with a range of 0 to 9,999.9 s/step
- Energy-saving capability (for predetermined temperature output control)
- ▶ Security: password protection available at no charge
- ▶ Three automated bake methods: contact, vacuum, proximity
- ▶ Bake plate auto sizing for 3-inch, 100-, 125-, 150-, and 200-mm substrates
- ▶ Temperature data recording
- Optional electronic lift pins (replace N<sub>2</sub> proximity for loading/unloading substrates from bake module). Program 1000 specific proximity heights above the surface in any sequence or combination. Height is programmed in 0.001-inch



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increments with an overall range of 0.000 to 0.750 inches.

- Ramping capability optional (8 specific set points within a single bake recipe)
- ► Spin speed: 0 to 6,000 rpm (12,000 rpm option at no charge; 16,000 rpm option available)
- Spin speed acceleration:
  0 to 30,000 rpm/s unloaded
  0 to 23,000 rpm/s for 200-mm substrate
  0 to 3,000 rpm/s for 6-inch × 6-inch × 0.250-inch photomask recessed chuck
- System capable of controlling third-party host software for high-end IDI/Cybor/Mykrolis positive displacement pumps
- ▶ Simultaneous dual automated dispense capability
- ▶ Bidirectional speed control/oscillating chuck
- ▶ Iteration software (recipe looping)
- ▶ Dispense or component outputs: 50
- ▶ In-process/dynamic speed/acceleration control

#### Precision

- ▶ Spin speed repeatability: within < 0.2 rpm
- ▶ Spin speed resolution: within < 0.2 rpm
- ▶ Substrate sizes: < 1 cm to 200 mm round; 7 inches × 7 inches square)</p>
- ► Temperature resolution: ± 0.1°C
- ▶ Temperature range: ambient to 300°C (400°C optional)
- ▶ Temperature uniformity: 0.3% across working surface

### Reliability

- Indirect drive system protects the spin motor from contact with process chemicals and solvents
- Vacuum and lid interlock
- ▶ Exceptional reliability and uptime
- ▶ 1-year full warranty on parts and labor
- Free remote technical support (phone, email, fax) for the life of the product
- ▶ Application process assistance for life of the product

## Bowl & Exhaust Hood Design

- ▶ All stainless steel construction
- ▶ Teflon® spin bowl for material compatibility
- ▶ Integrated bowl ring to eliminate material migration
- Optional stainless steel bowl (for all-stainless-steel construction)
- ▶ Optional polyethylene bowl (educational package) available
- ▶ Optional polyethylene liners available
- ▶ Optional polyethylene/Teflon® splash ring
- ▶ Closed and optional open lid designs for process flexibility
- ▶ Drain and exhaust ports located in the bottom of bowl
- Exhausted hood for removal of process chemicals
- ▶ Optional nitrogen purge for inert spin/bake environment

#### Utilities

▶ Voltage ranges: 100, 110-125, 208-240 VAC, 50/60 Hz

▶ Power requirements: 1793 watts (16 amps)

Drain Port: ¾ inch OD
 Exhaust Port: 1 inch OD
 Vacuum: 20 to 25 inches Hg
 Bowl Exhaust: 20 to 50 cfm

▶ Bake Plate Exhaust: 1 inch OD; 5 to 10 cfm

▶ Nitrogen or CDA (for automated dispenses): 70 psi



Cee® 200CBX shown with optional nitrogen diffusers on the bake plate



Optional programmable lift pins on the bake plate (shown) allow for precise process control

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F.6.6.7046.A Effective Date: 09/02/2010